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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE	
INFORMATION DISCLOSURE STATEMENT BY APPLICANT	Atty. Docket No. (Opt.) UBAT1520
Applicant Gregory R. Hanson et al.	
Application Number 10/649,474	Filed August 26, 2003
For Spatial Heterodyne Interferometry for Reflection and Transmission (SHIRT) Measurements	
Group Art Unit 2877	Examiner Unknown

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

<p align="center"><u>Certificate of Mailing Under 37 C.F.R. 1.8</u></p> <p>I hereby certify that this correspondence is being deposited with the U.S. Postal Service as First Class Mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on <u>June 14</u>, 2004.</p> <p align="center"> Laura M. McGuire</p>
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Applicants respectfully request, pursuant to 37 C.F.R. §§ 1.56, 1.97 and 1.98, that the art listed on the attached PTO-1449 form be considered and cited in the examination of the above-identified application. A copy of the art is enclosed for the convenience of the Examiner. Furthermore, pursuant to 37 C.F.R. §§ 1.97(g) and (h), no representation is made that a search has been made or that this art is material to patentability of the present application.

While Applicants believe no fees are due, if any fees are due, the Commissioner is hereby authorized to charge Deposit Account No. 50-0456 of Gray Cary Ware & Freidenrich LLP.

Applicants respectfully submit that the claims of Applicants' above-referenced patent application are patentably distinguishable from these references.

Respectfully submitted,

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Dated: June 11, 2004

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				Examiner Name	Unknown
Sheet	1	of	1	Attorney Docket Number	2500940-991520 (UBAT1520)
NON-PATENT LITERATURE DOCUMENTS					
	C1	Edgar Volkl, "Introduction to Electron Holography", pp. 133-138, published by Kluwer Academic/Plenum Publishers, New York, 1999.			
	C2	Jacob et al., "High Resolution Photomask Transmission and Phase Measurement Tool", Metrology, Inspection and Process Control for Microlithography XVI, Proceedings of SPIE Vol. 4689, pp. 70-82, 2002.			
	C3	Thomas et al., "Direct to Digital Holography for Semiconductor Wafer Defect Detection and Review", Design, Process Integration, and Characterization for Microelectronics, Proceedings of SPIE Vol. 4692, pp. 180-194, 2002.			
	C4	"Phase Contrast Microscopy" Authors unknown, date unknown			
Examiner Signature				Date Considered	